ELECTRONIC INFORMATION DISCLOSURE STATEMENT

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Title of Invention	METHODS AND SYSTEMS FOR RETICLE INSPECTION AND DEFECT REVIEW USING AERIAL IMAGING

Application Number: 10/679617
Confirmation Number: 3334
First Named Applicant: Stan Stokowski
Attorney Docket Number: 5589-04101
Search string: (6636301 or 6614520 or 6529621).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6636301	2003-10-21	Kvamme et al.			
	2	6614520	2003-09-02	Bareket et al.			
	3	6529621	2003-03-04	Glasser et al.			

Signature

Examiner Name	Date
	2/22/06

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Form PTO-1449 (modified) List of Patents and Publications For Applicant's Information Disclosure Statement (Use several sheets if necessary)	ATTY. DKT. NO. 5589-04101 APPLICANT: Stokowski et al. FILING DATE: October 6, 2003	SERIAL NO. 10/679,617 GROUP: 2877

U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO
RM	A1	1 061 358	12/2000	EP			
RM	A2	1 061 571	12/2000	EP			
RM	A3	1 065 567	1/2001	EP			
RM	A4	1 066 925	1/2001	EP			
RM	A5	1 069 609	1/2001	EP			
RM	A6	99/22310	5/1999	WO			
RM	A7	99/25004	5/1999	WO			
RM	A8	99/38002	7/1999	WO			
RM	A9	99/41434	8/1999	WO			
RM	A10	99/59200	11/1999	WO			
RM	A11	00/03234	1/2000	WO			
RM	A12	00/36525	6/2000	WO			
RM	A13	00/68884	11/2000	WO			
RM	A14	00/70332	11/2000	WO			
RM	A15	01/09566	2/2001	WO			
RM	A16	01/40145	6/2001	WO			

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

RM	A17	Otsu, "A Threshold Selection Method from Gray-Level Histograms," IEEE Transactions on Systems, Man, and Cybernetics, Vol. SMC-9, No. 1, January 1979, pp. 62-66.

EXAMINER: [signature] DATE CONSIDERED: 2/22/06

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the patent owner.

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EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
RAR		6466315	10/2002	Karpol et al.			
RAR		6268093	07/2001	Kenan et al.			
RAR		6184976	02/2001	Park et al.			
RAR		6691052	02/2004	Maurer			

U.S. PATENT APPLICATION DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
RAR		2003/0207475	11/2003	Nakasuji et al.			

FOREIGN PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

RAR	E1	Barty et al., "Aerial Image Microscopes for the inspection of defects in EUV masks," Proceedings of SPIE, Vol. 4889, 2002, pp. 1073-1084.
RAR	E2	Yan et al., "Printability of Pellicle Defects in DUV 0.5 μm Lithography," SPIE Vol. 1604, 1991, pp. 106-117.

EXAMINER: RAR DATE CONSIDERED: 2/22/06

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US Patent Documents

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init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5980187	1999-11-09	Verhovsky			
	2	5619548	1997-04-08	Koppel			
	3	6104835	2000-08-15	Han			
	4	6233719	2001-05-15	Hardikar et al.			
	5	5991699	1999-11-23	Kulkarni et al.			
	6	5689614	1997-11-18	Gronet et al.			
	7	4247203	1981-01-27	Levy et al.			
	8	4347001	1982-08-31	Levy et al.			
	9	4378159	1983-03-29	Galbraith			
	10	4448532	1984-05-15	Joseph et al.			
	11	4532650	1985-07-30	Wihl et al.			
	12	4555798	1985-11-26	Broadbent, Jr. et al.			
	13	4579455	1986-04-01	Levy et al.			

	14	4633504	1986-12-30	Wihl
	15	4641967	1987-02-10	Pecen
	16	4758094	1988-07-19	Wihl
	17	4766324	1988-08-23	Saadat et al.
	18	4805123	1989-02-14	Specht et al.
	19	4845558	1989-07-04	Tsai et al.
	20	4877326	1989-10-31	Chadwick et al.
	21	4926489	1990-05-15	Danielson et al.
	22	5189481	1993-02-23	Jann et al.
	23	5563702	1996-10-08	Emery et al.
	24	5572598	1996-11-05	Wihl et al.
	25	5737072	1998-04-07	Emery et al.
	26	5889593	1999-03-30	Bareket
	27	6052478	2000-04-18	Wihl et al.
	28	6076465	2000-06-20	Vacca et al.
	29	6122046	2000-09-19	Almogy
	30	6137570	2000-10-24	Chuang et al.
	31	6141038	2000-10-31	Young et al.
	32	6175645	2001-01-16	Elyasaf et al.
	33	6282309	2001-08-28	Emery
	34	6363166	2002-03-26	Wihl et al.

Signature

Examiner Name	Date
	2/22/06